

FIG.1

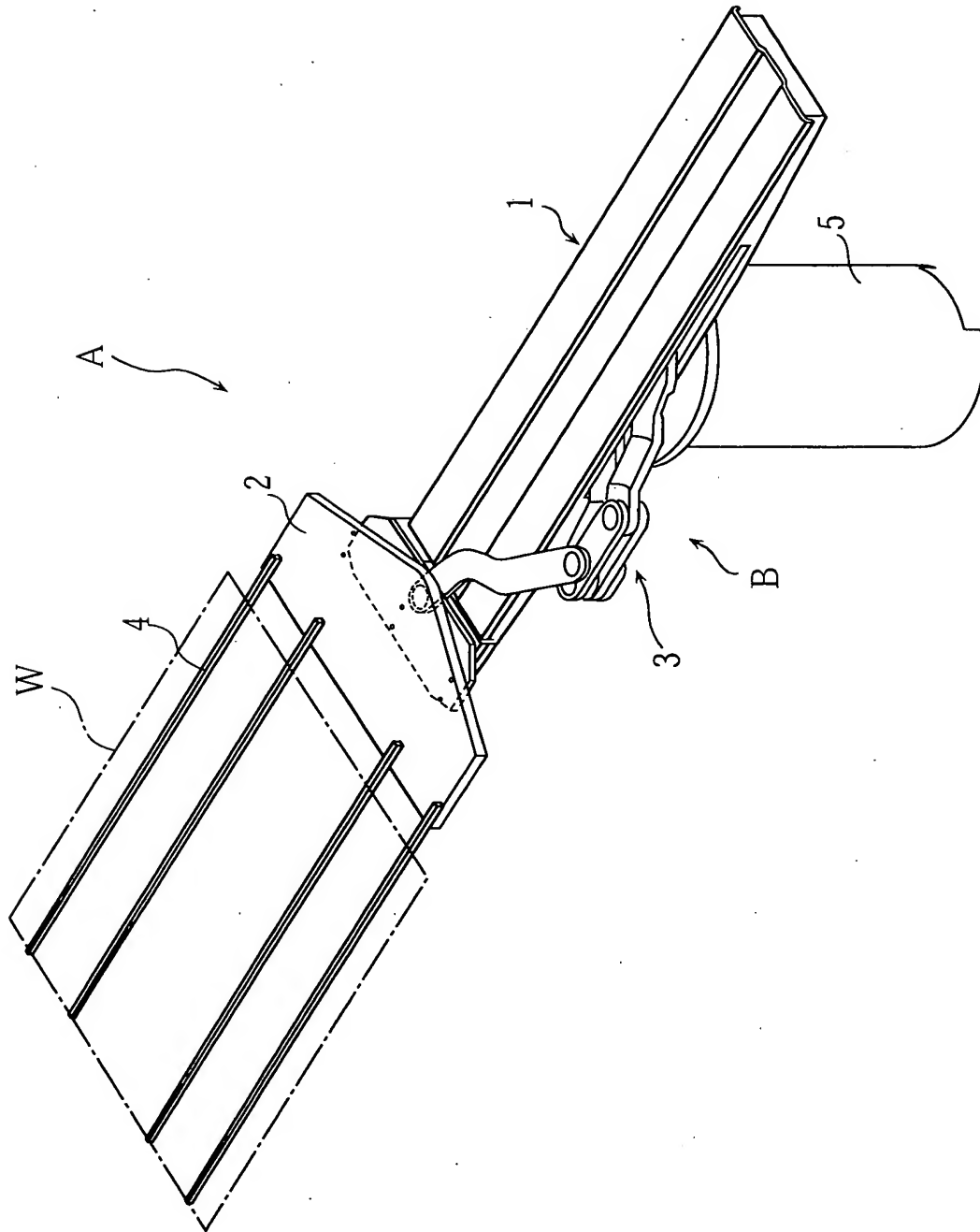
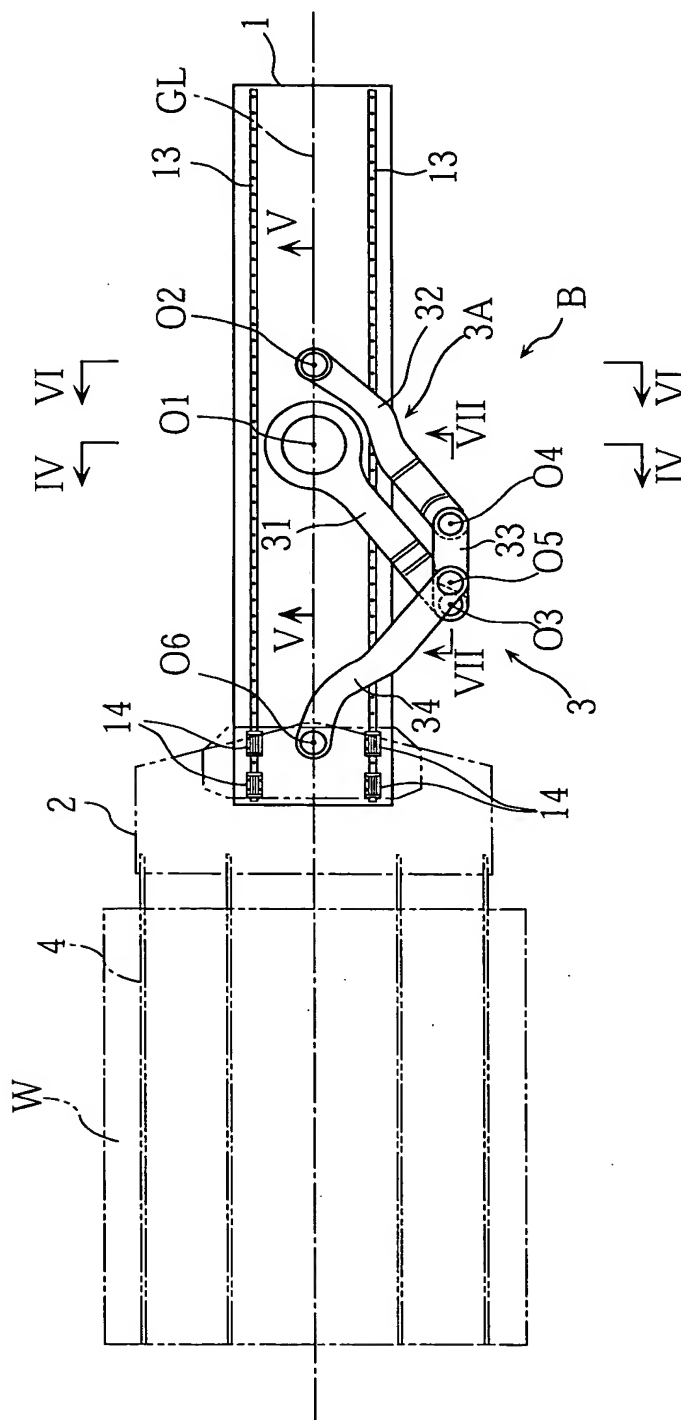


FIG.2



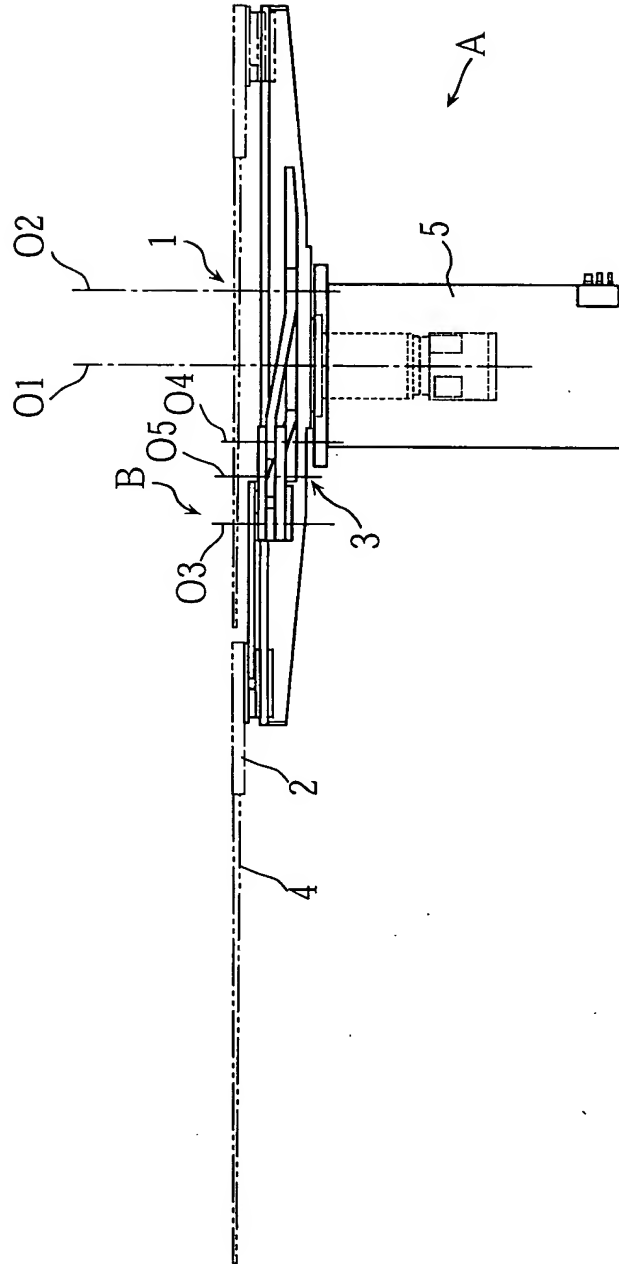


FIG. 3

FIG. 4

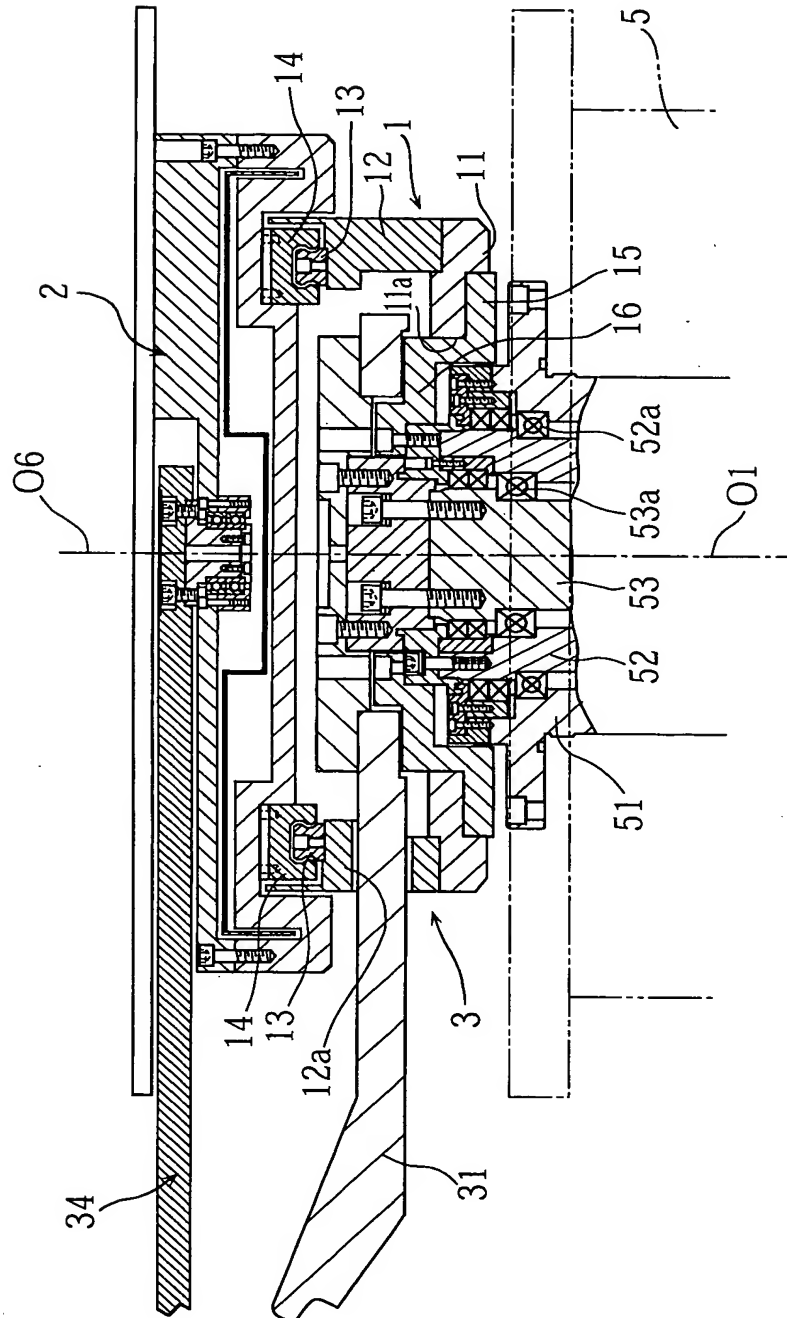
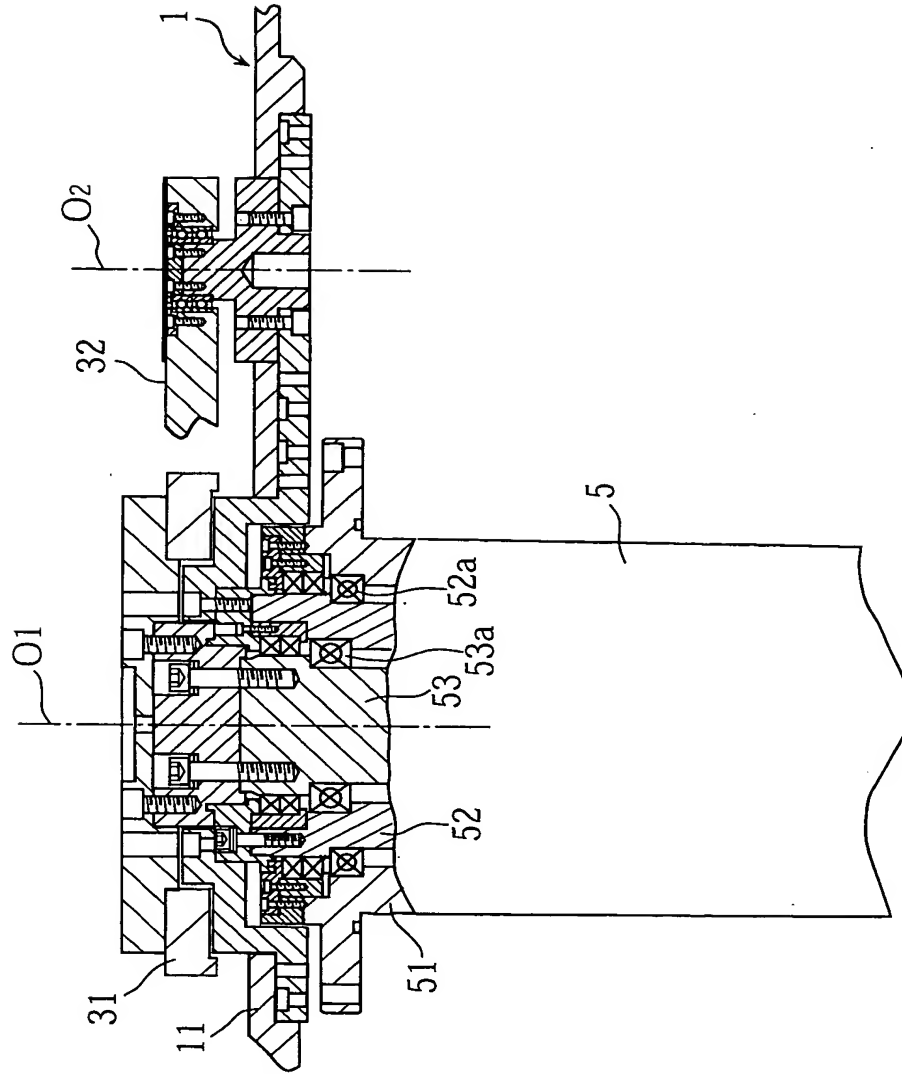


FIG. 5



5



FIG. 7

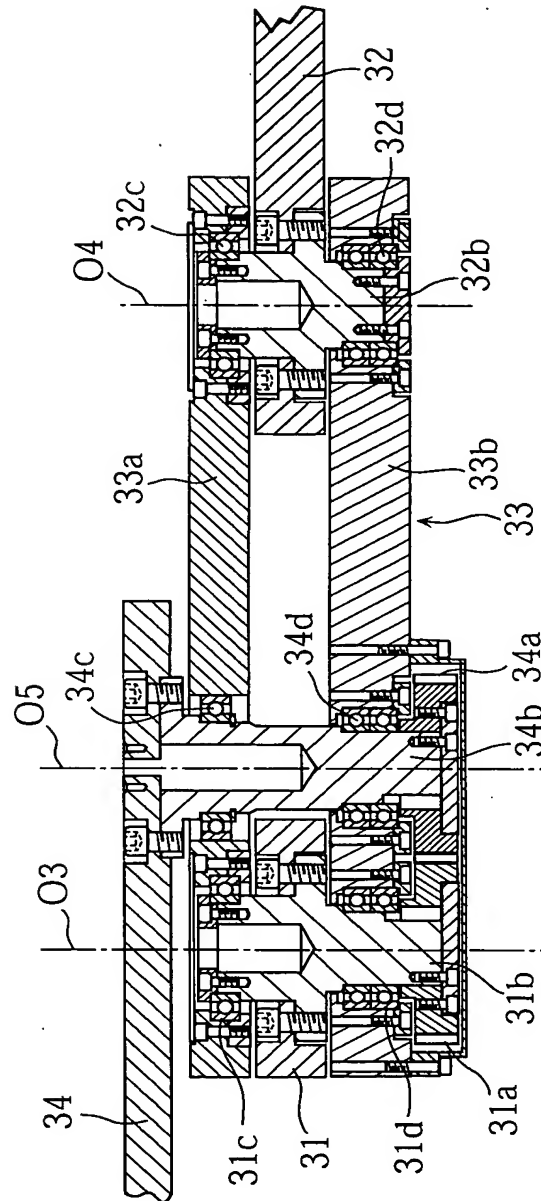


FIG. 8

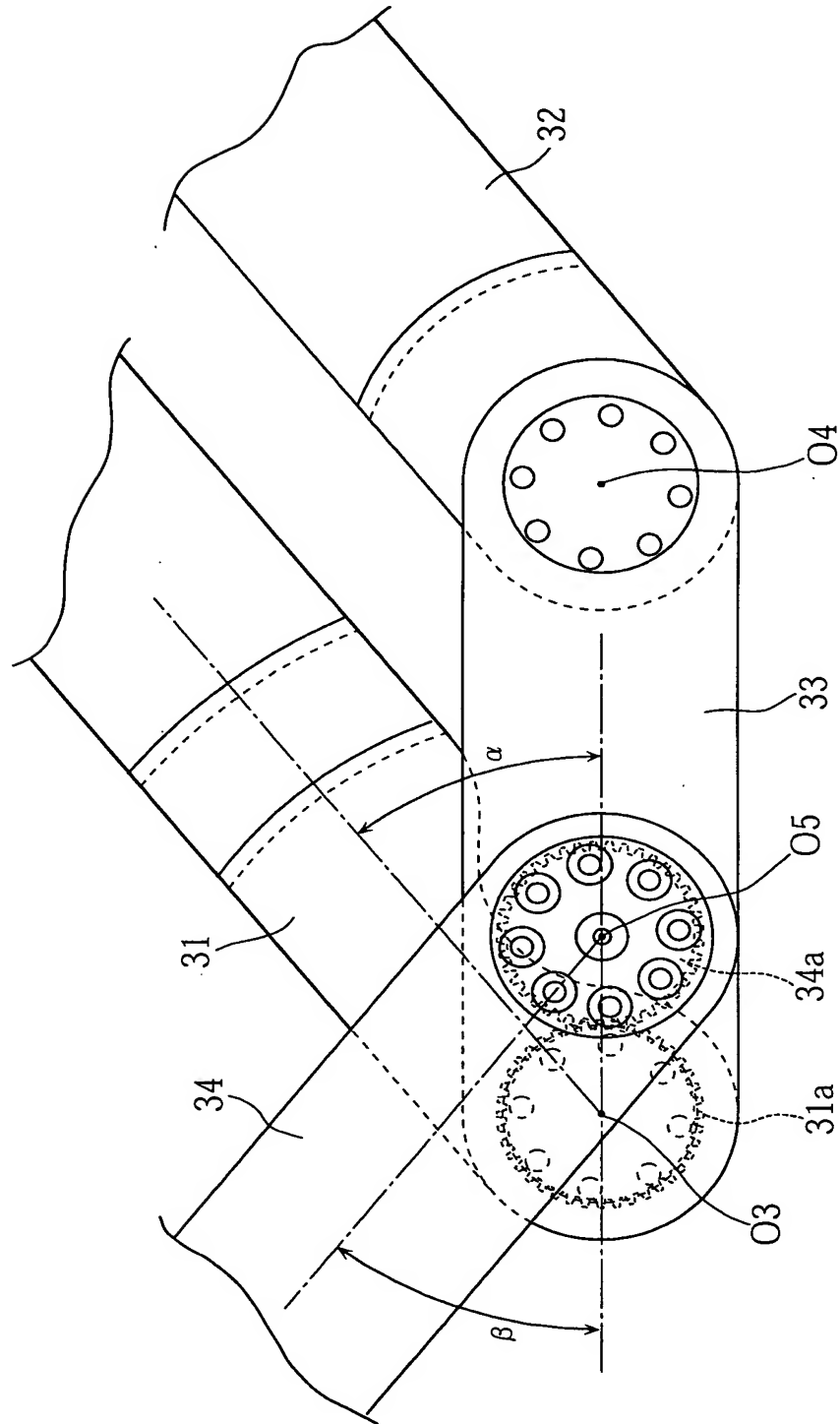


FIG. 9

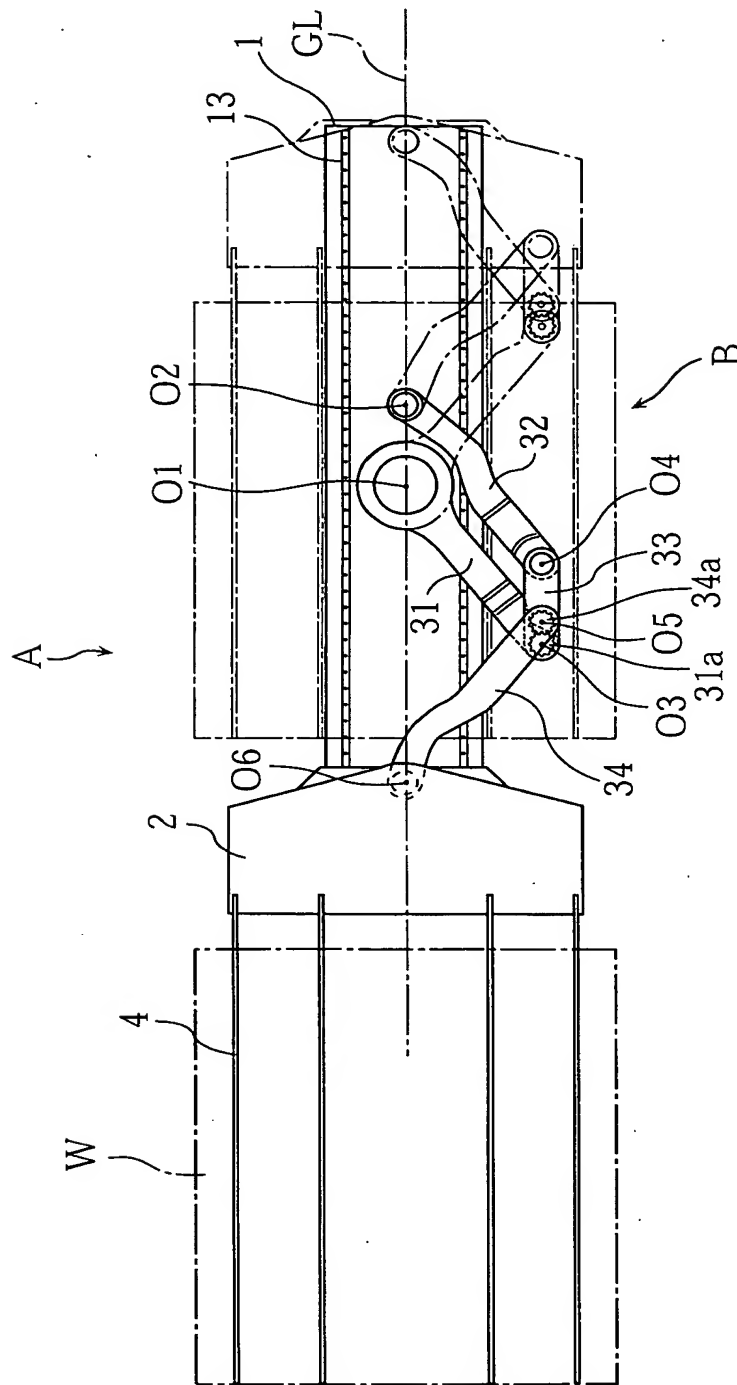


FIG.10

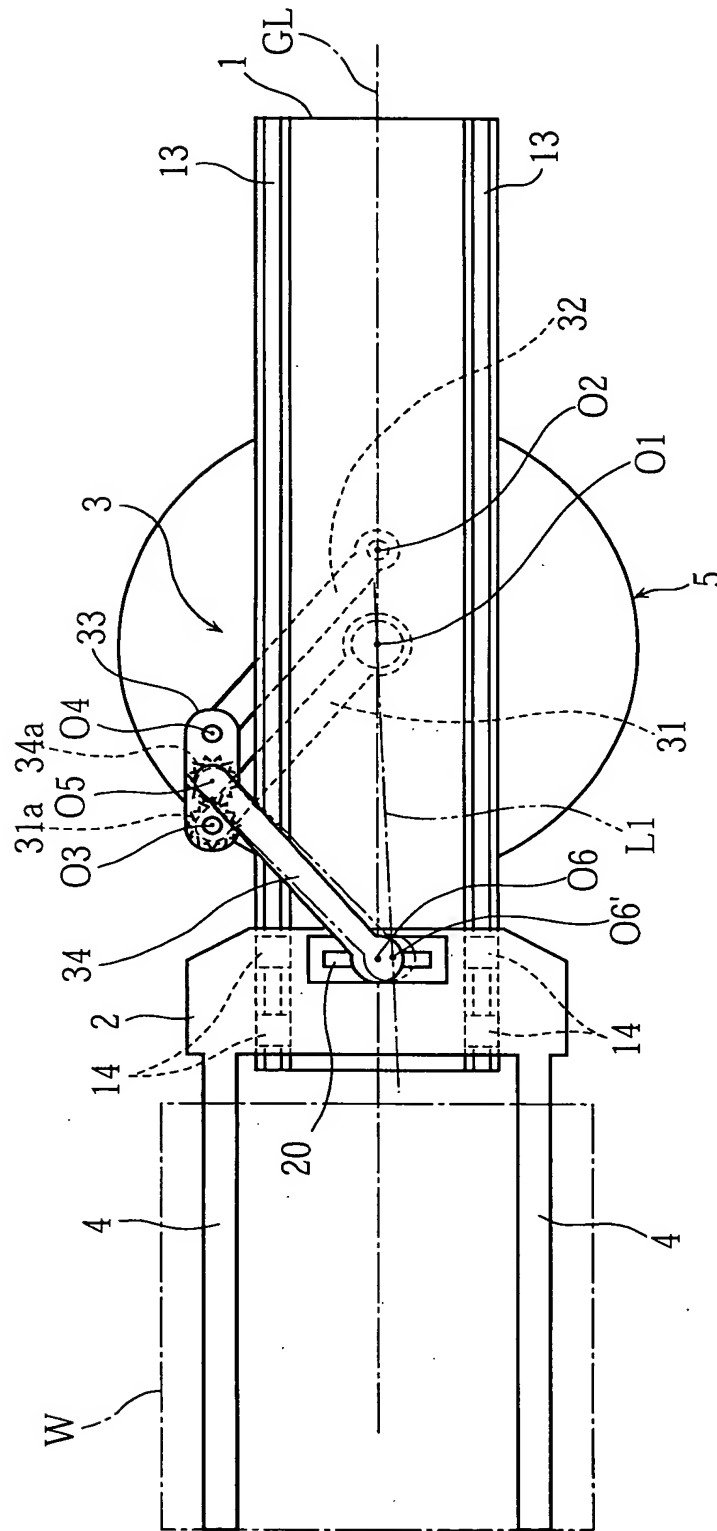


FIG.11

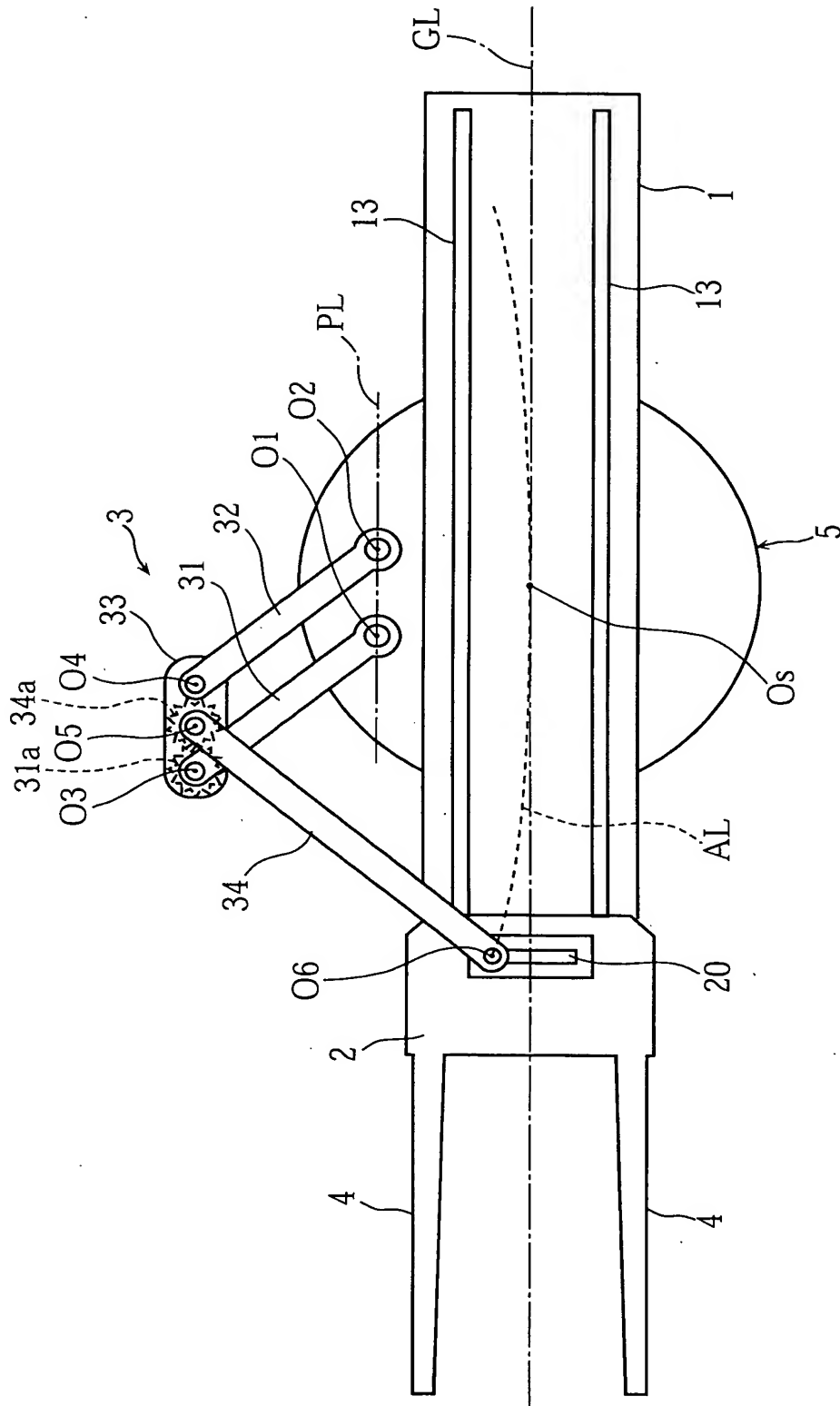


FIG.12

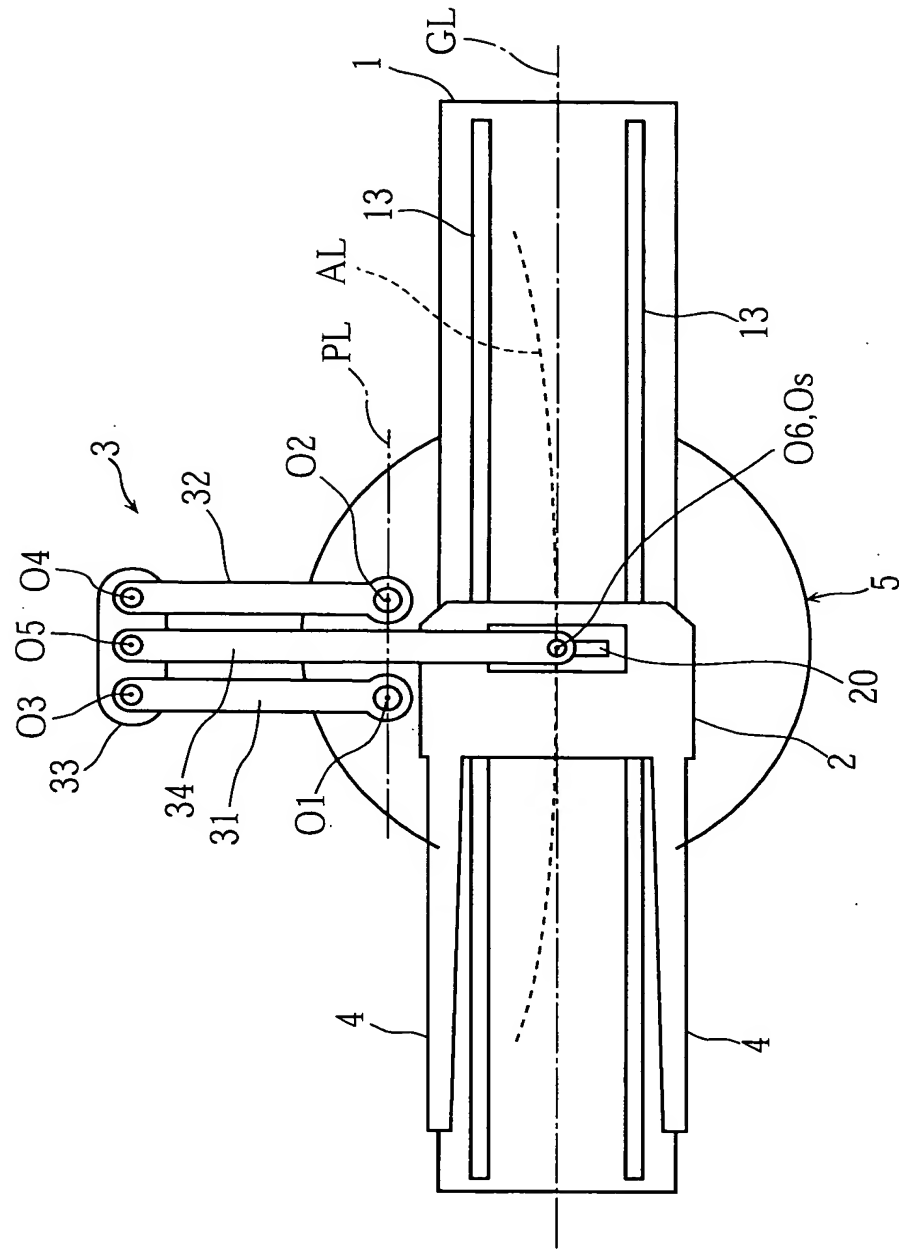


FIG.13

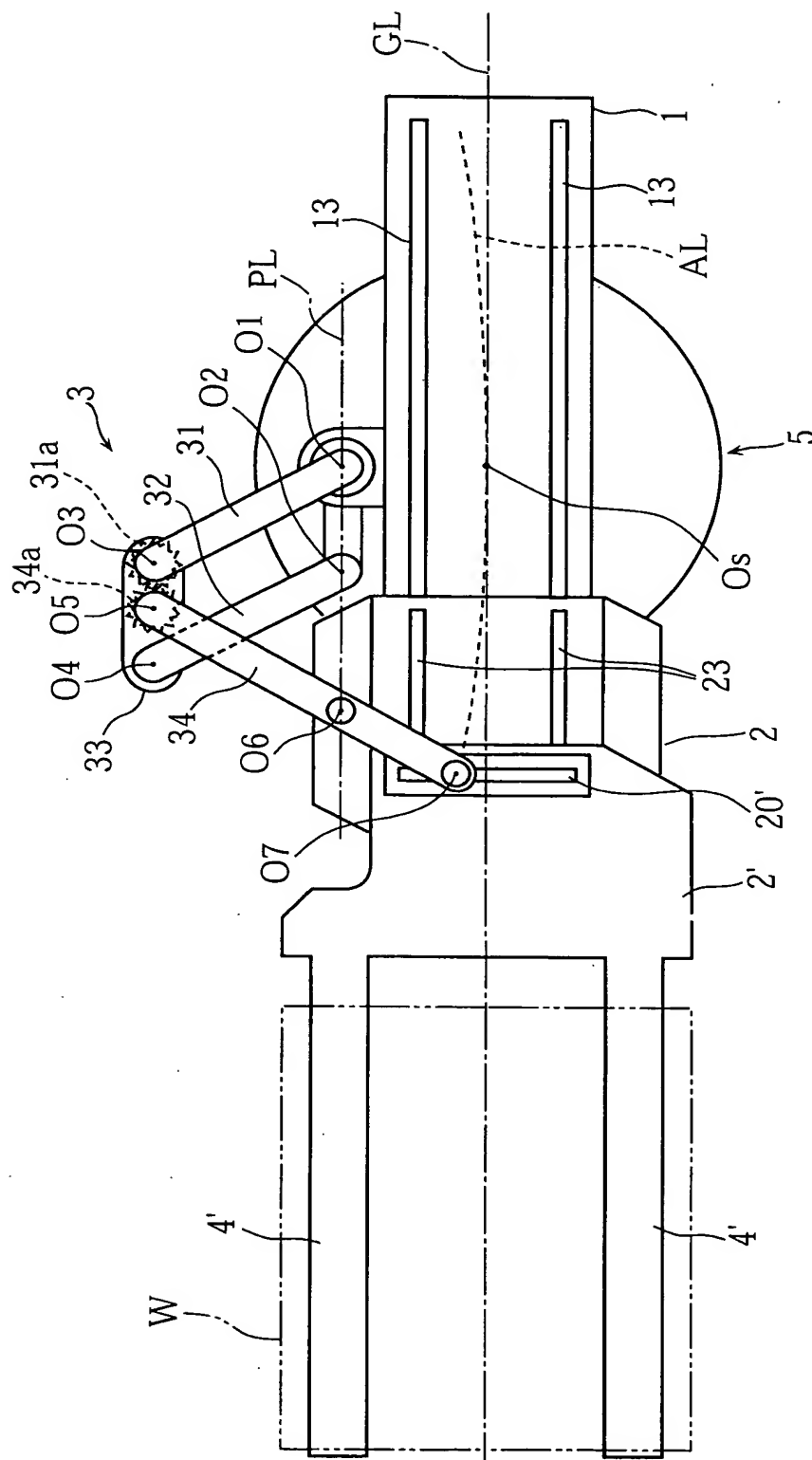


FIG. 14

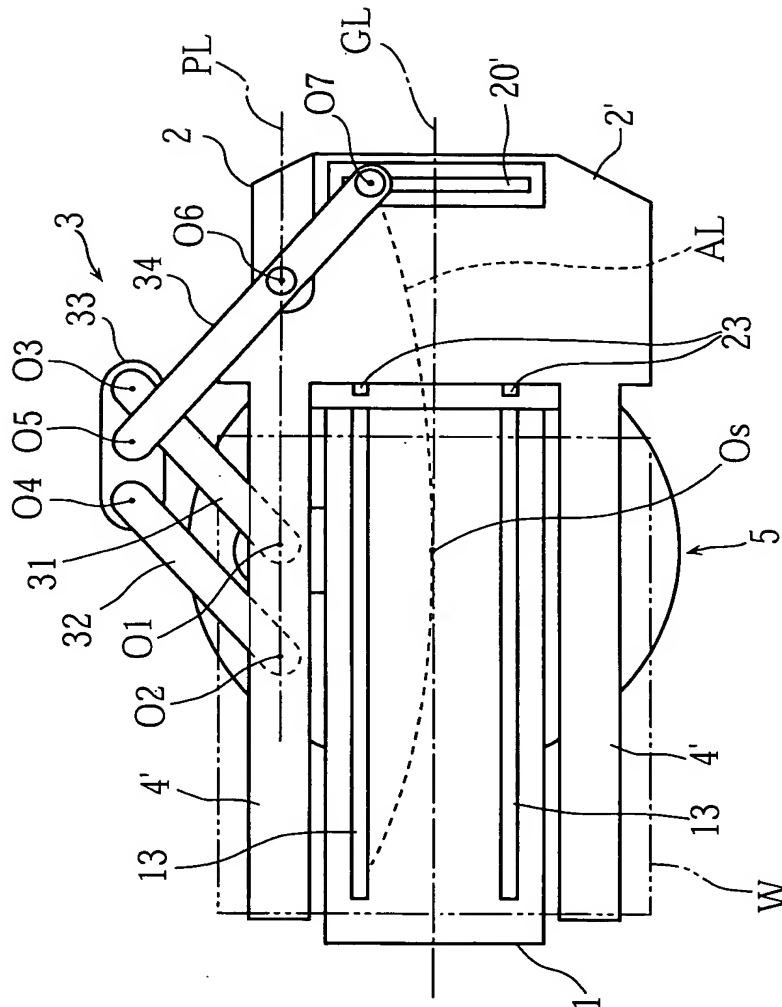
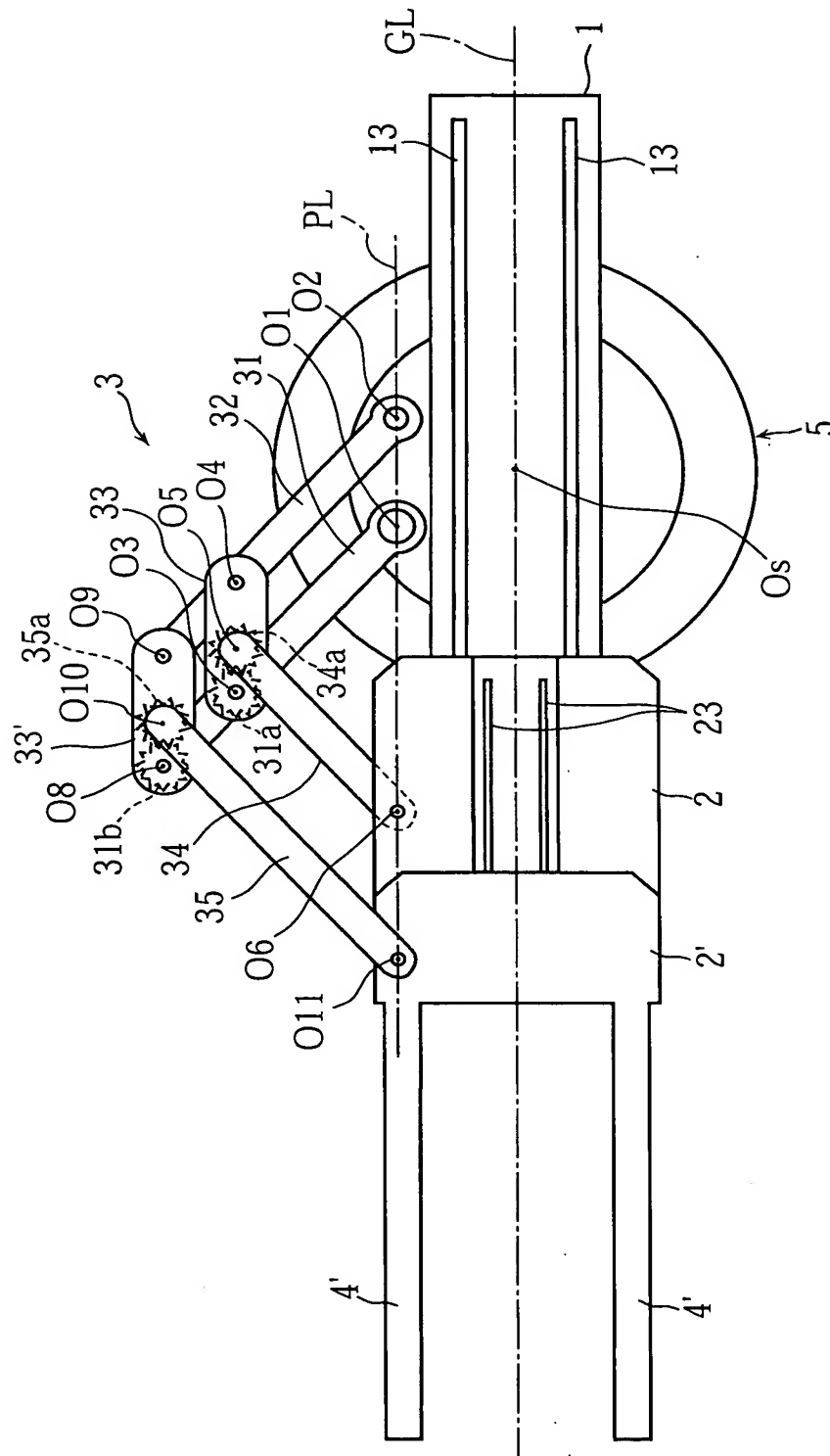
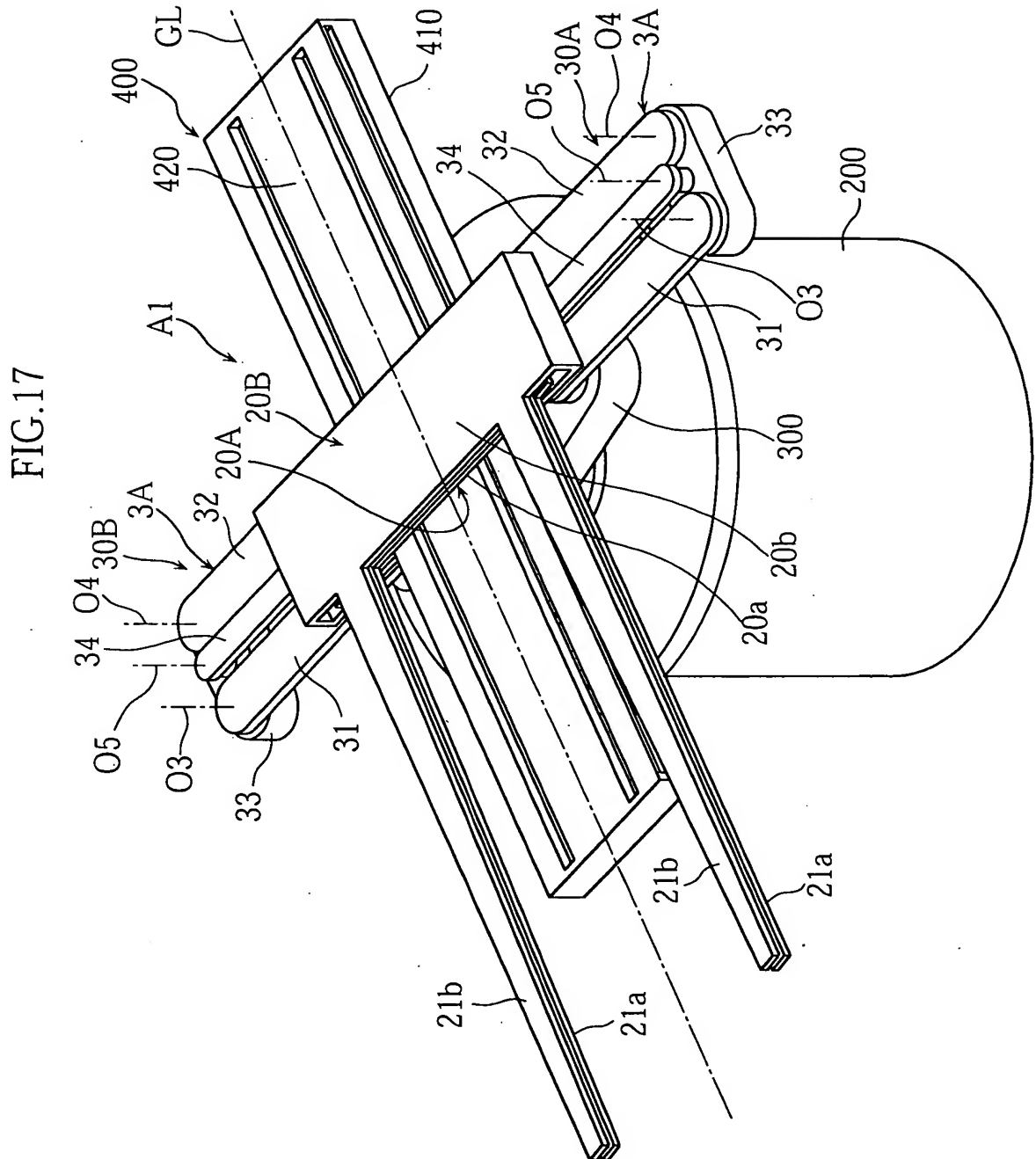
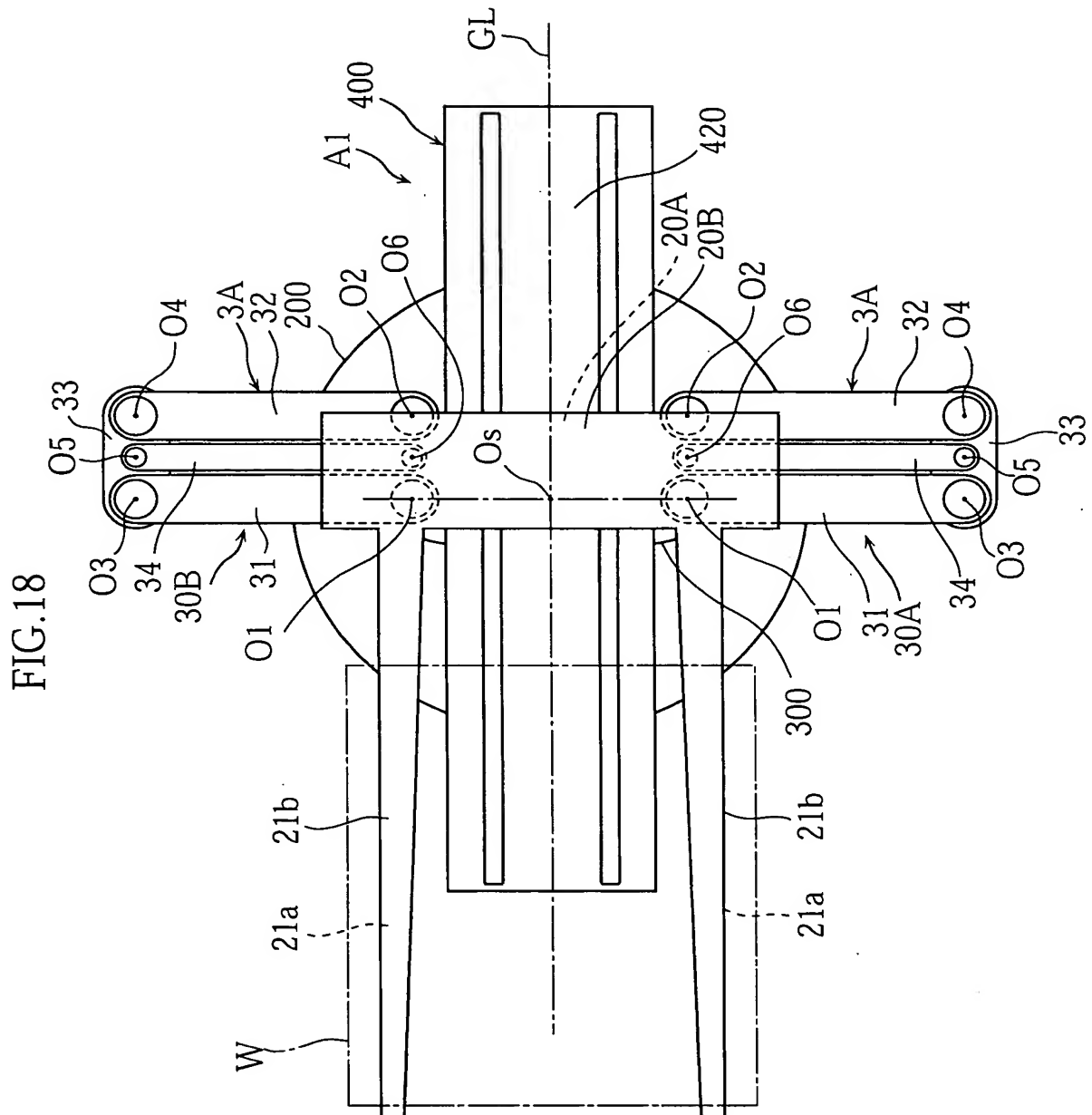


FIG. 15







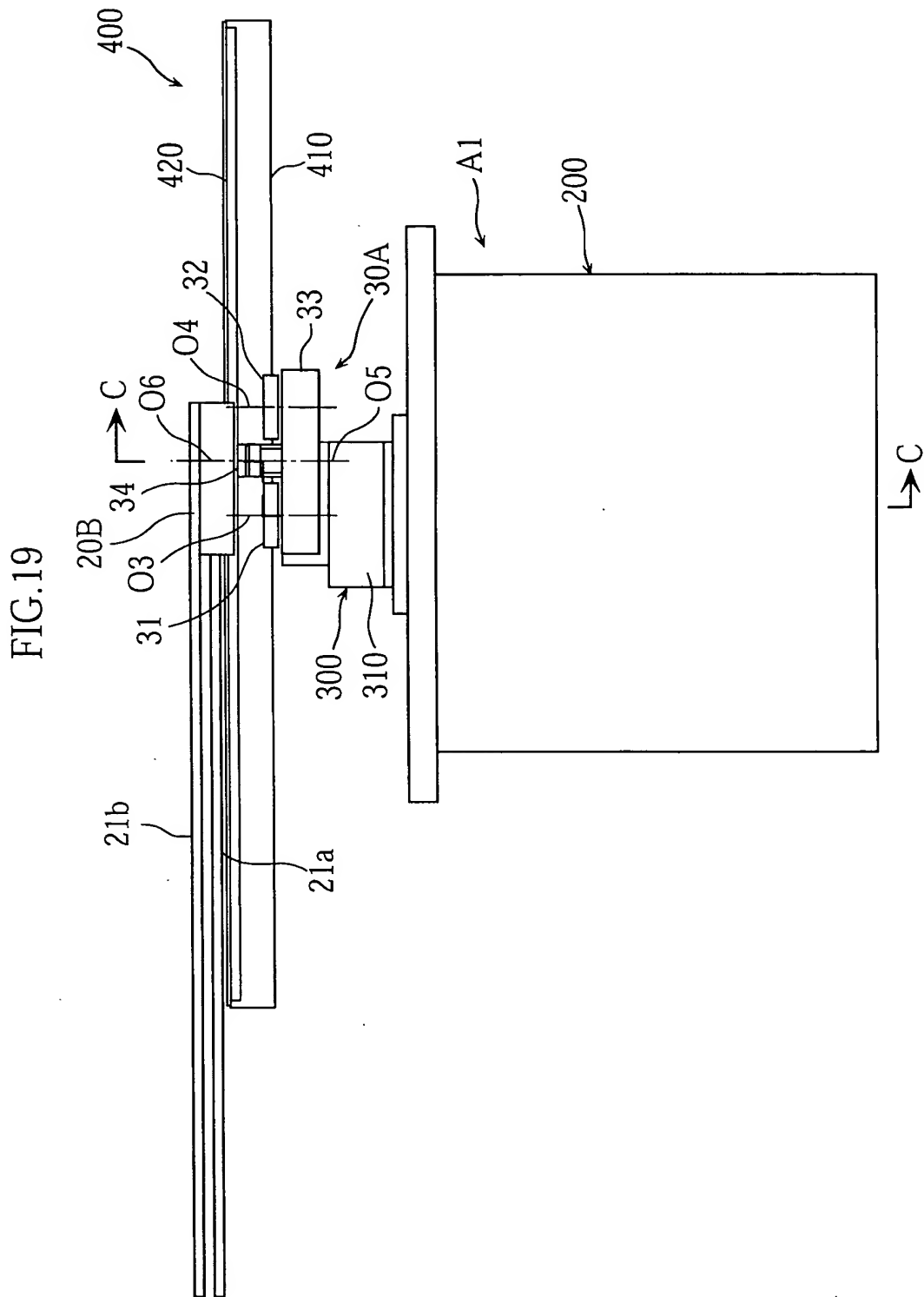


FIG. 21

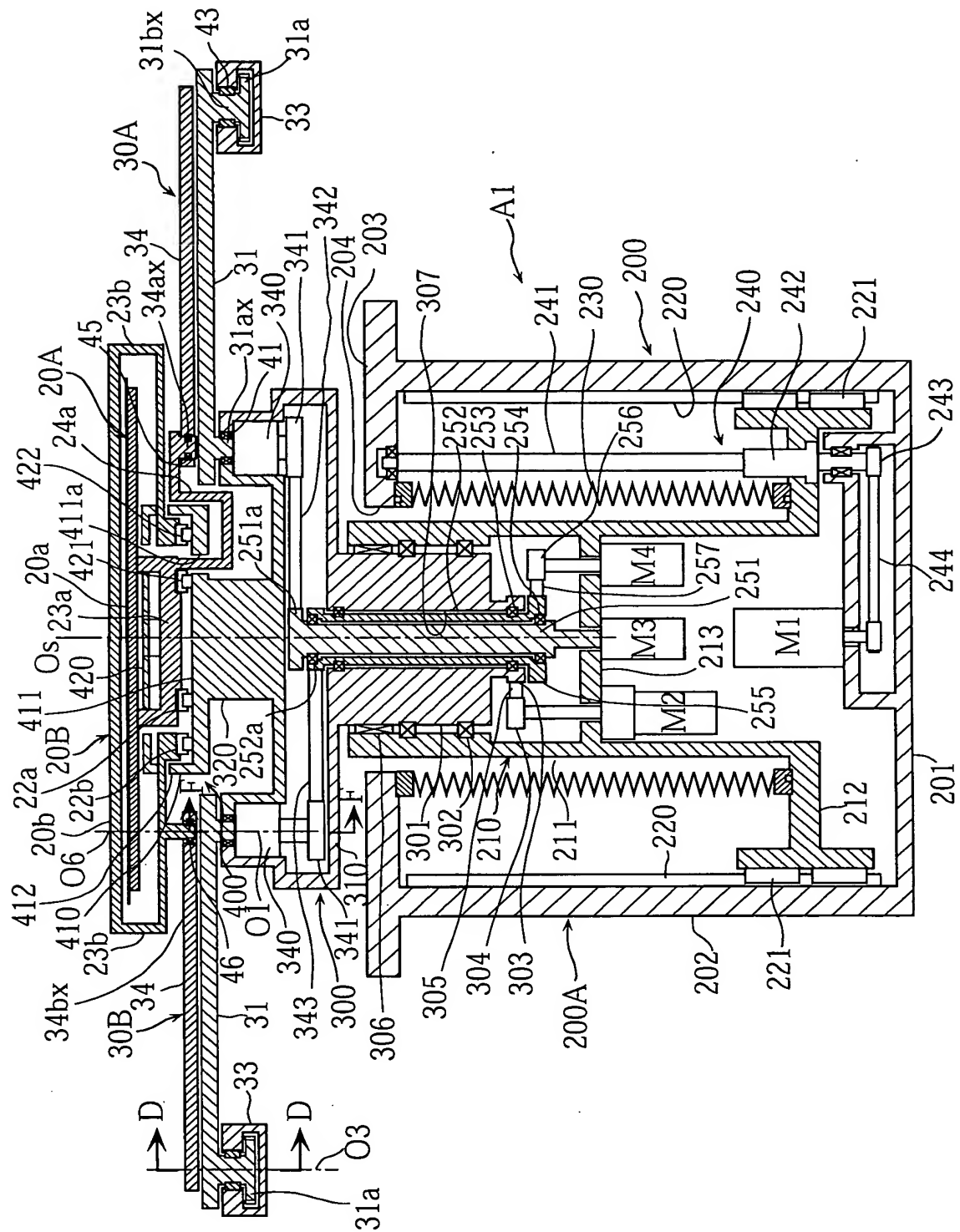


FIG.22

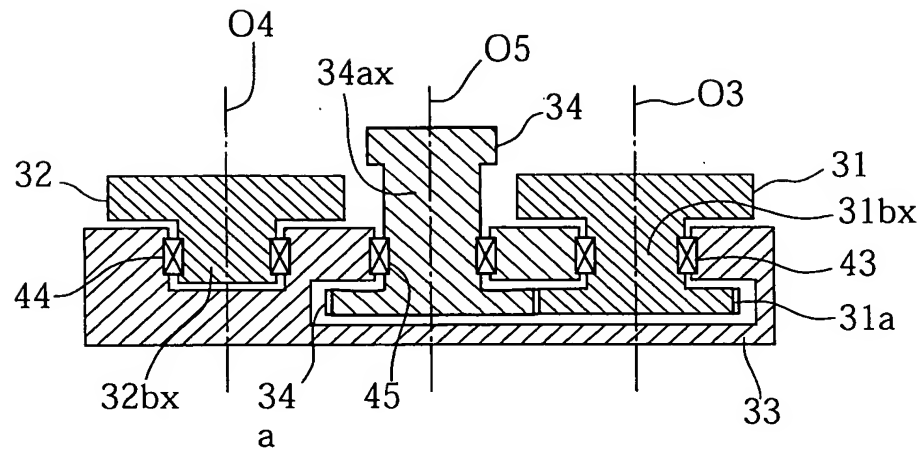
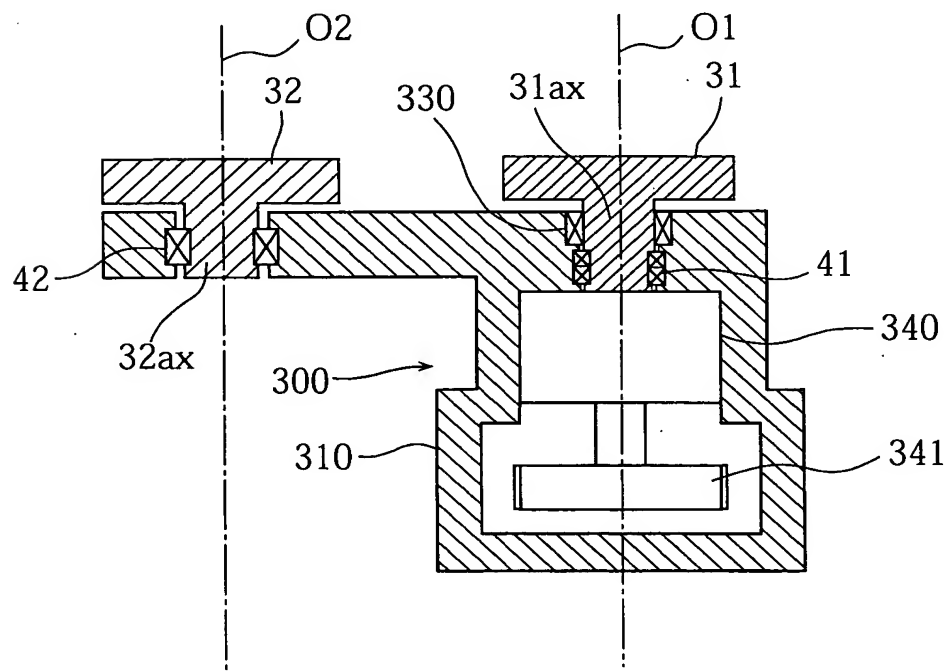
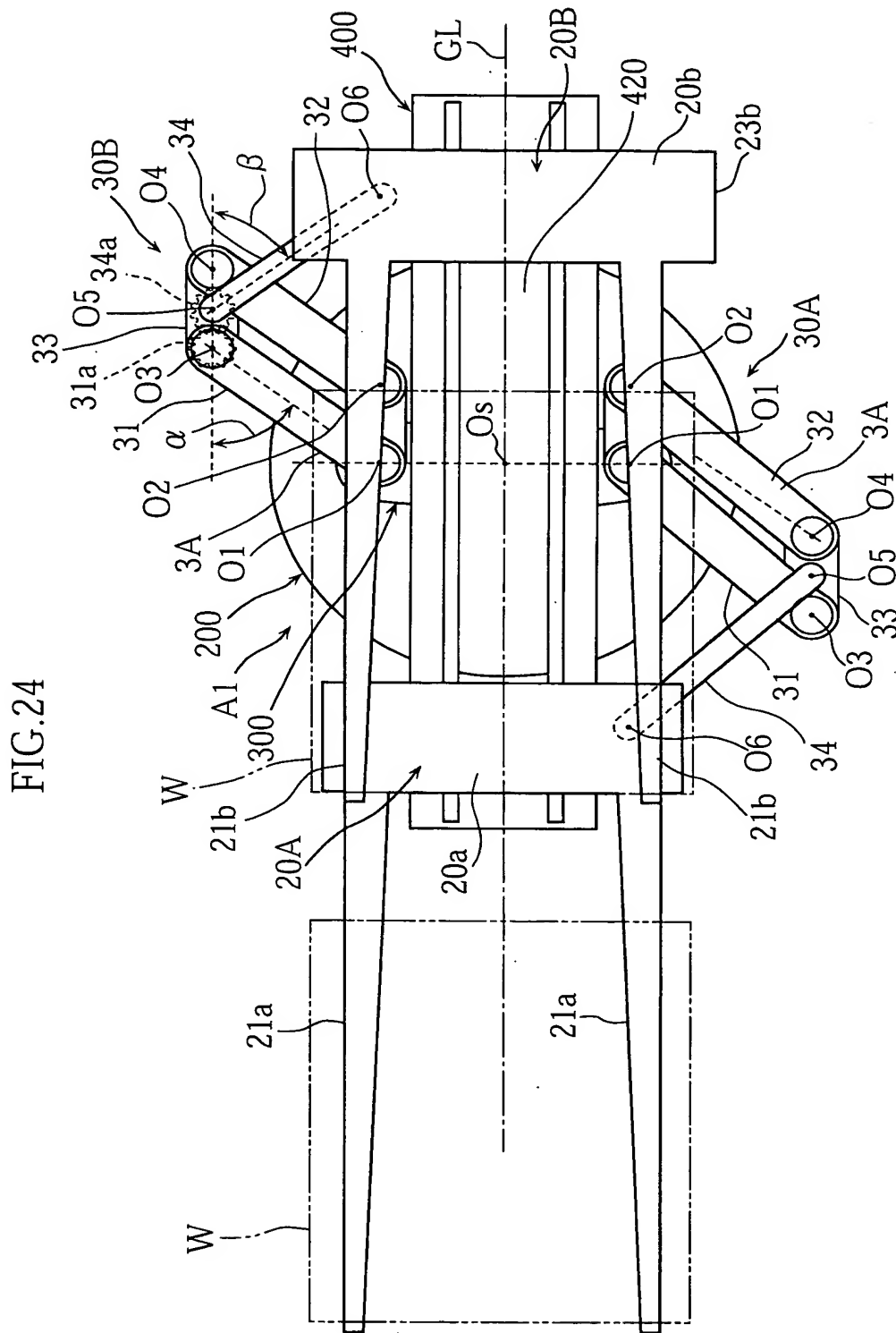
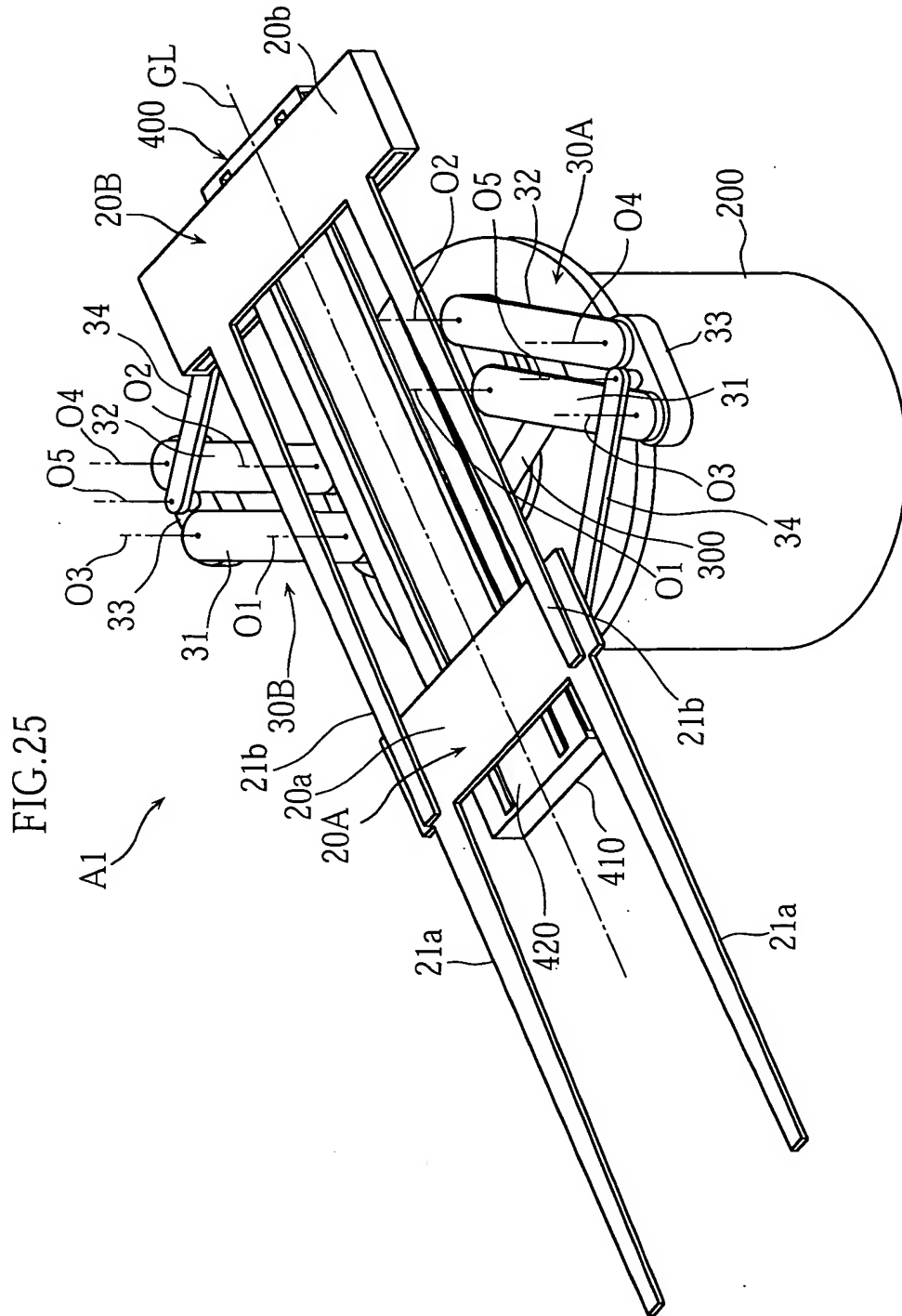
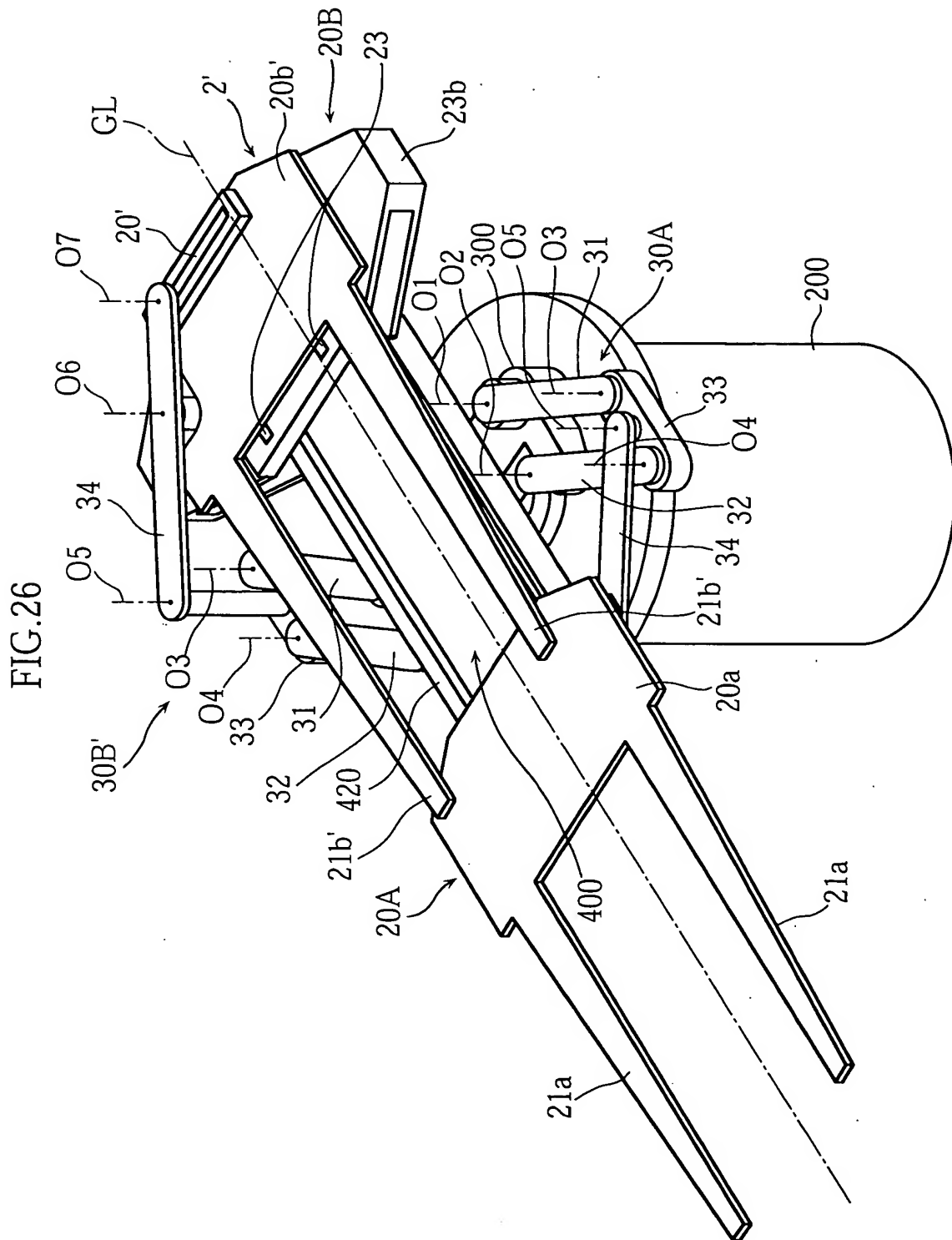


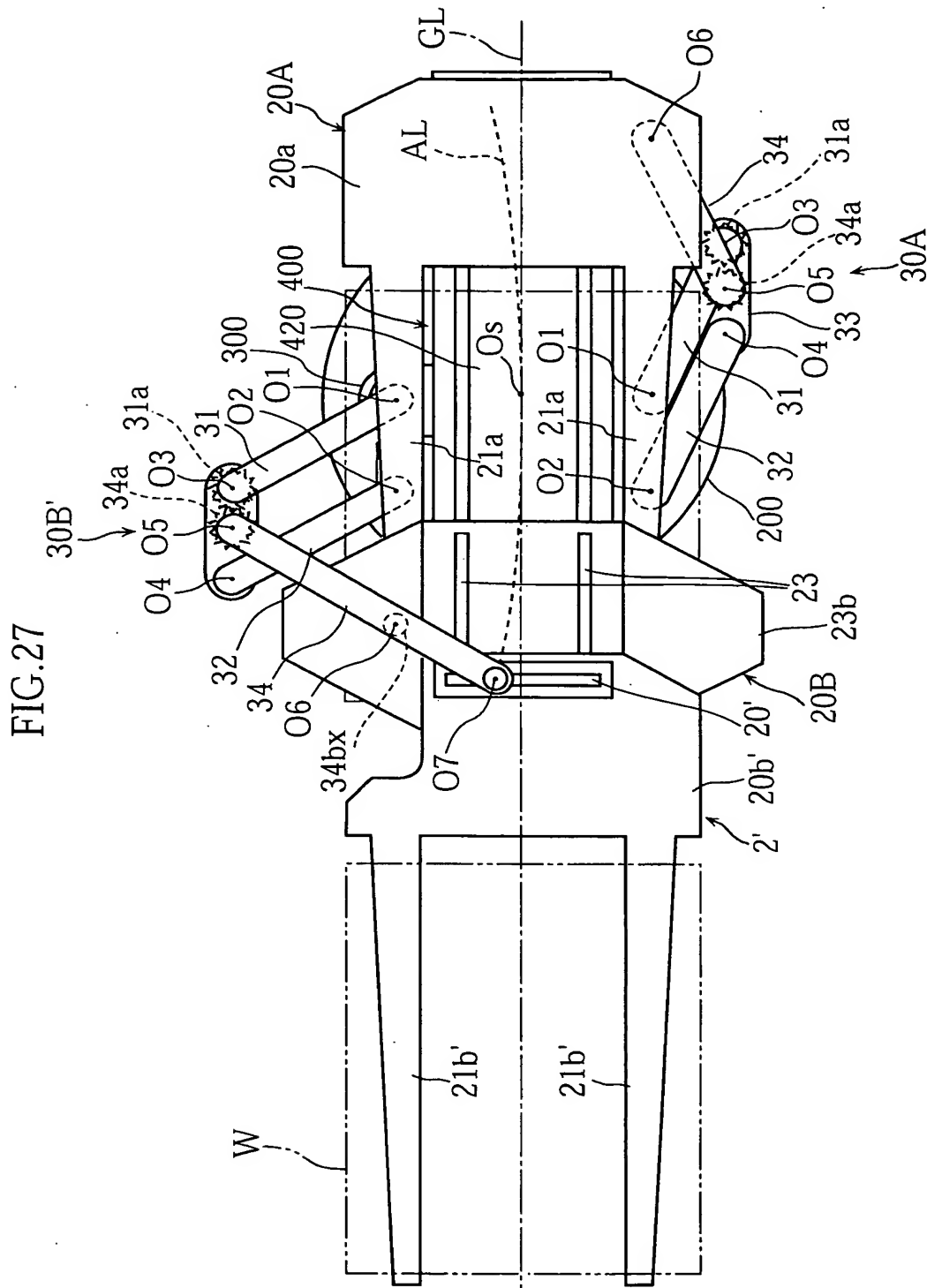
FIG.23

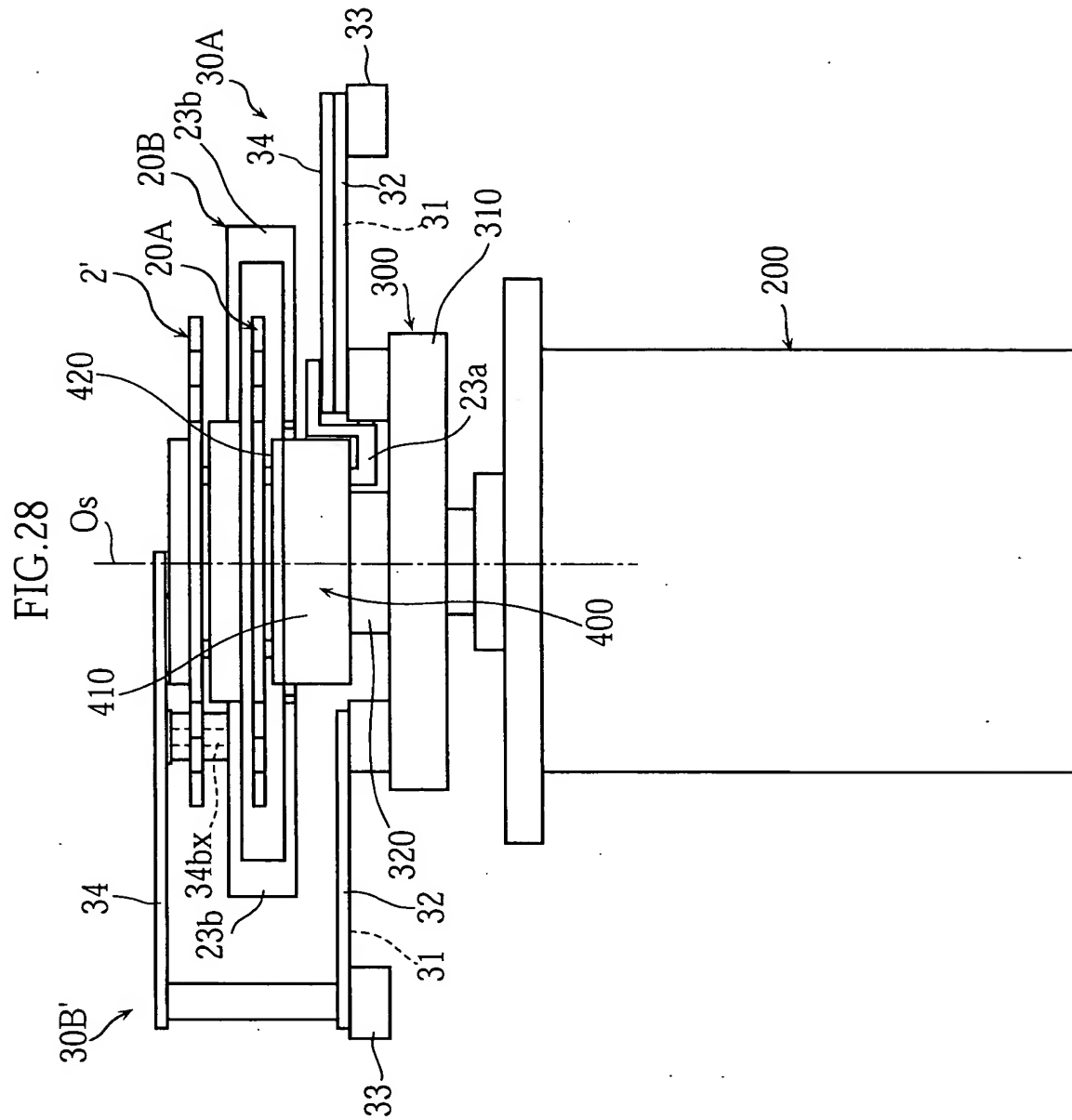












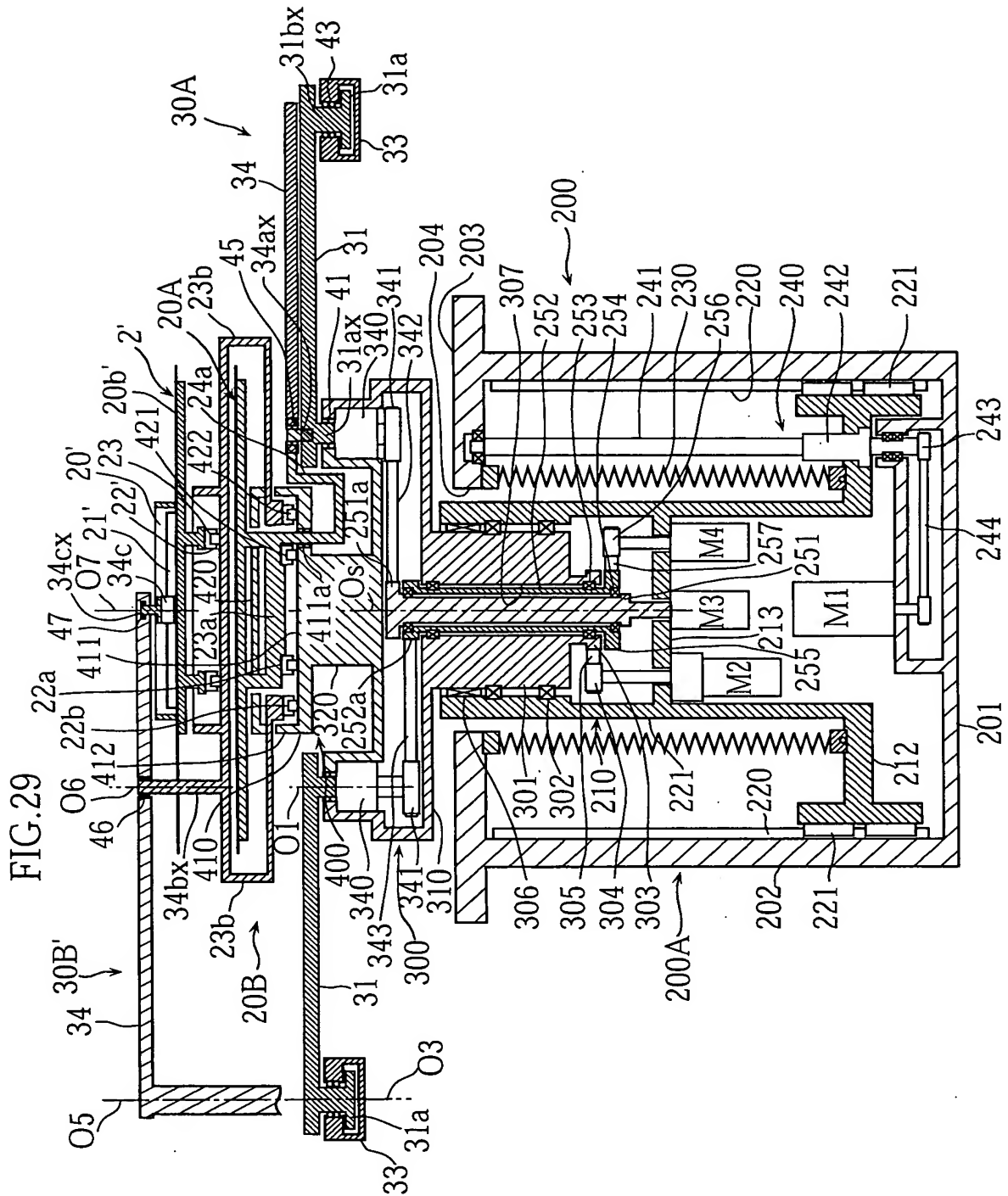


FIG.30A

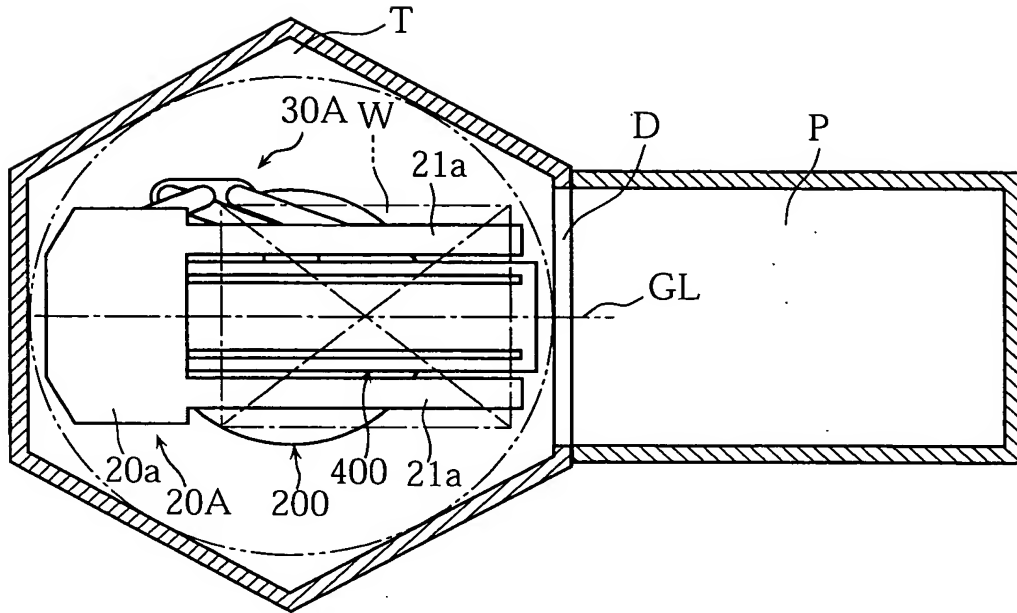


FIG.30B

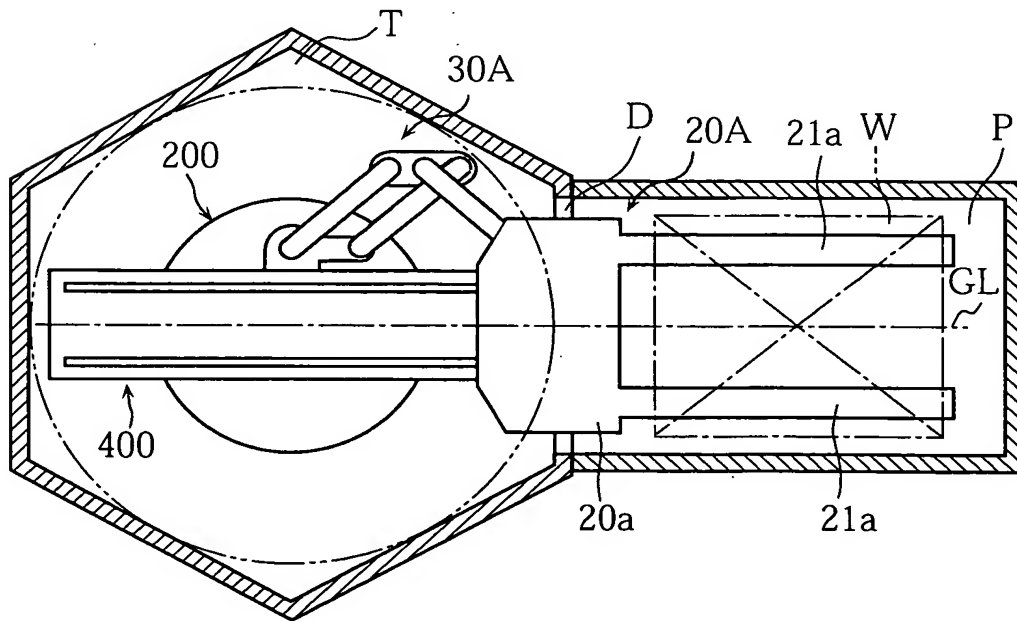


FIG.31A

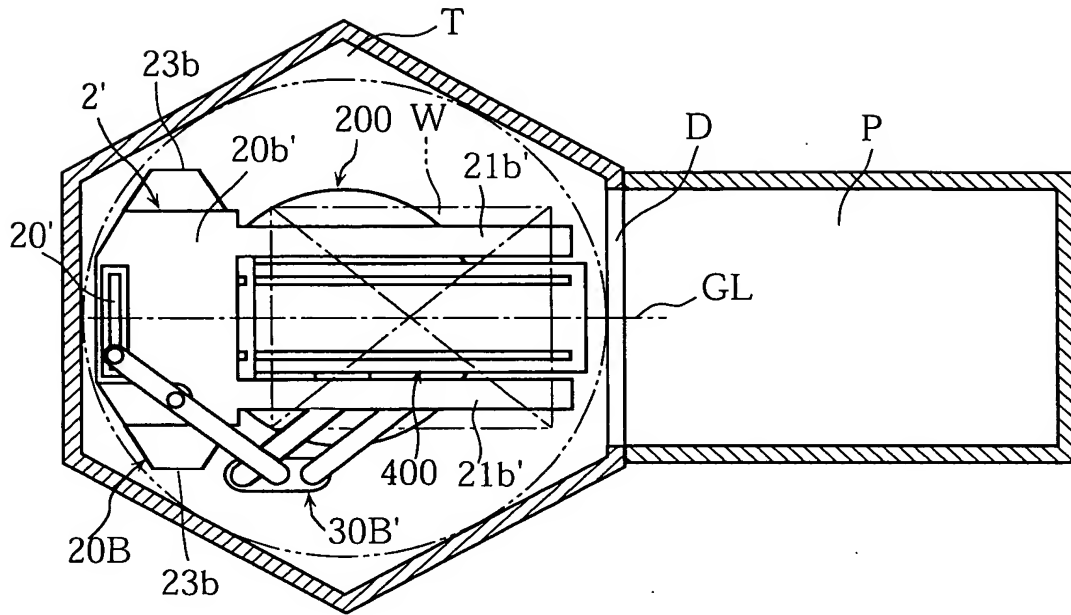


FIG.31B

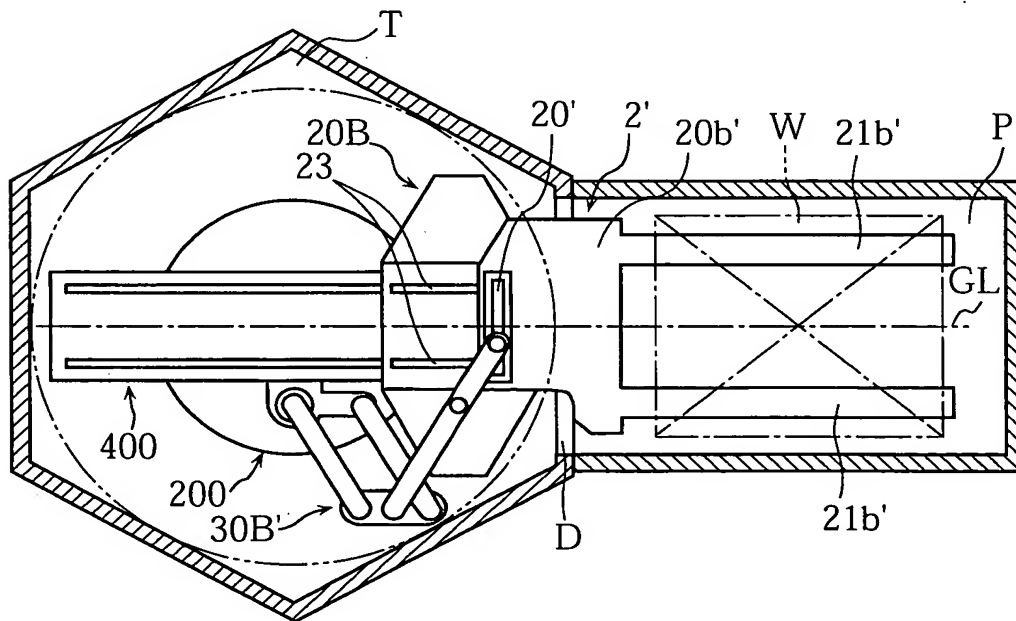


FIG.32

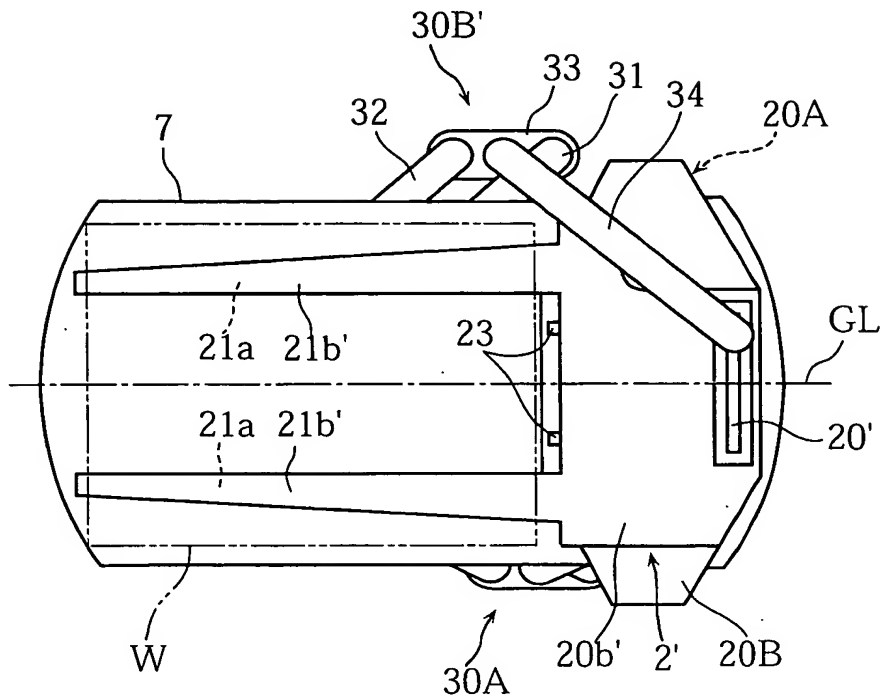


FIG.33

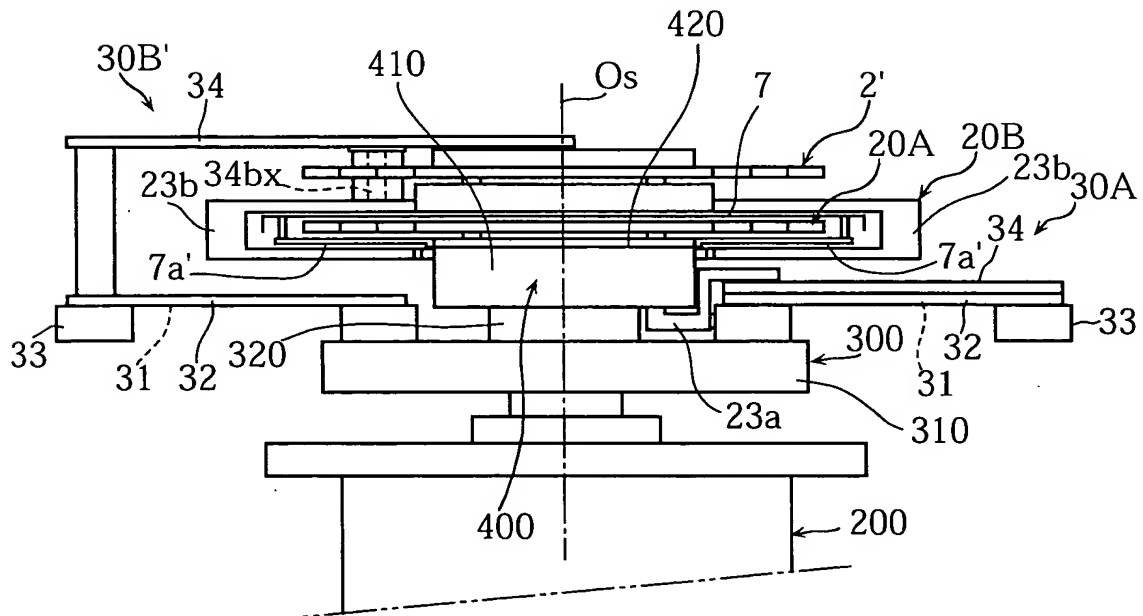


FIG.34A

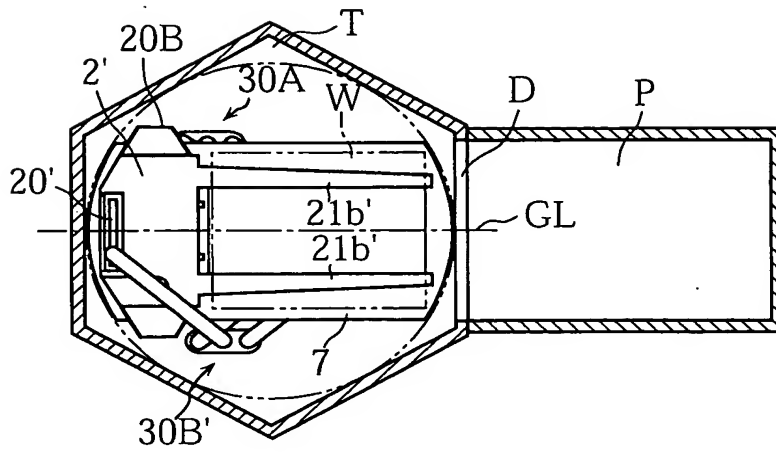


FIG.34B

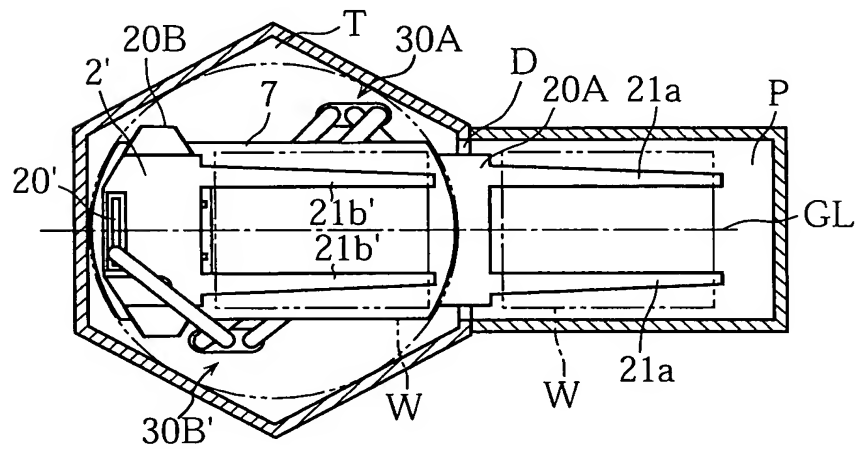


FIG.34C

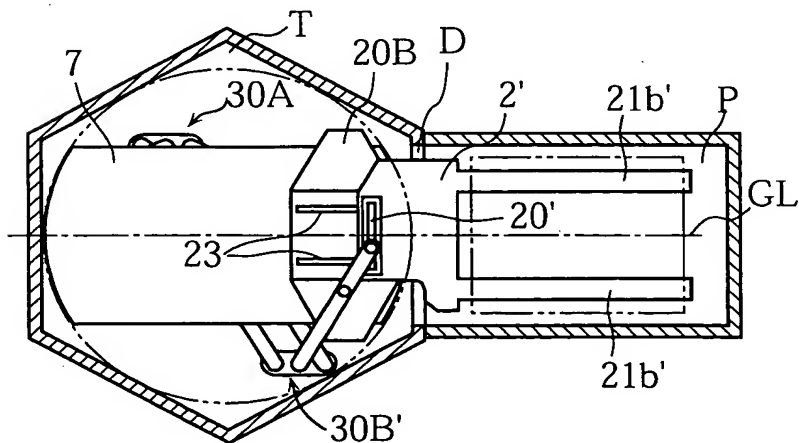


FIG. 35C
後退位置

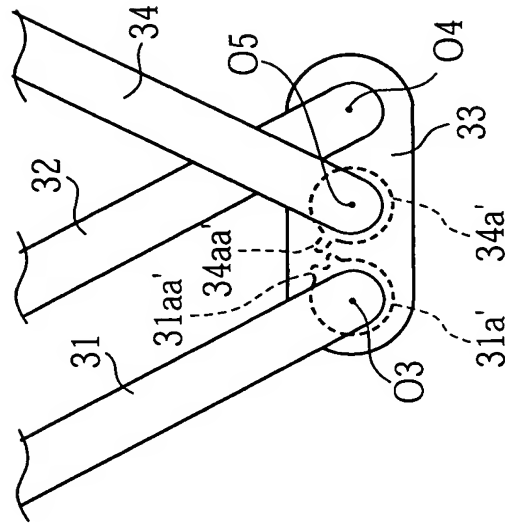


FIG. 35B
思案点付近

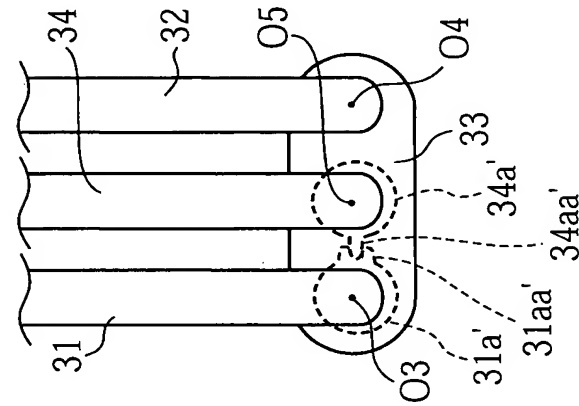


FIG. 35A
前進位置

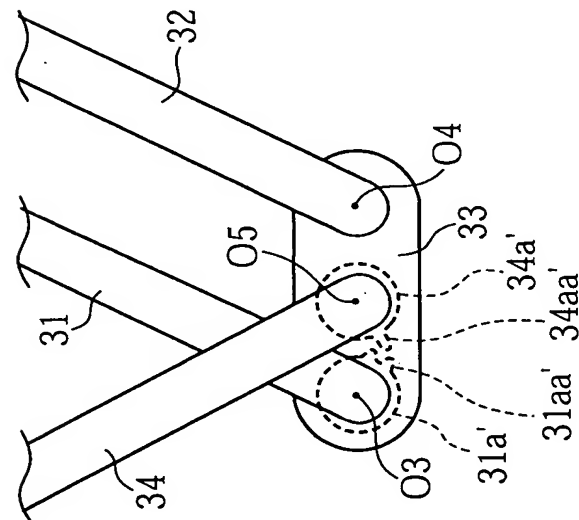


FIG.36
関連技術

